

**Amendments to the Claims:**

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) An actuator comprising:  
an insulating substrate;  
a pair of silicon arms, doped with an impurity, having respective ~~one~~ end parts connected to ~~both~~ opposite end faces of the insulating substrate;  
~~a piezoelectric part formed on a surface opposite from the surface connected to the insulating substrate in each silicon arm~~ each silicon arm provided at a surface, opposite from the surface connected to the insulating substrate, with a piezoelectric part; and  
~~a first electrode formed on a surface opposite from the surface opposing the silicon arm in each piezoelectric part~~ each piezoelectric part provided with a first electrode at a surface opposite a surface facing the respective silicon arm.
2. (Currently Amended) An actuator according to claim 1, further comprising ~~a second electrode formed on the surface formed with the piezoelectric part in the silicon arm~~ each silicon arm provided with a second electrode at the same surface that the respective piezoelectric part is provided at.
3. (Original) An actuator according to claim 1, wherein the insulating substrate is constituted by glass.
4. (Original) An actuator according to claim 1, wherein the piezoelectric part is a single-layer piezoelectric film.
5. (Original) An actuator according to claim 1, wherein the piezoelectric part has a laminate structure comprising alternately laminated piezoelectric and electrode films.
6. (Original) An actuator according to claim 4, wherein the piezoelectric film is constituted by PZT.

7. (Original) An actuator according to claim 1, wherein the first electrode comprises a multilayer structure including a topmost layer constituted by Au or Pt.

8. (Currently Amended) A method of making an actuator, the method comprising the steps of:

forming a piezoelectric film pattern on one surface each of two silicon substrates doped with an impurity;

forming an electrode film on the piezoelectric film pattern;

bonding the two silicon substrates, each formed with the piezoelectric film pattern and electrode film, to ~~both~~ opposite sides of an insulating substrate, respectively, such that the piezoelectric film patterns are oriented outward;

cutting a block having a predetermined form from a laminated substrate constituted by the two silicon substrates and insulating substrate laminated together; and

forming a silicon arm by cutting the block after partly removing the insulating substrate in the block on one side.

9. (Original) A method of making an actuator according to claim 8, further comprising the step of forming an electrode pattern on the silicon substrate.

10. (Original) A method of making an actuator according to claim 8, wherein the insulating substrate is constituted by glass.

11. (Original) A method of making an actuator according to claims 8, wherein the piezoelectric film pattern is constituted by PZT.